



Attorney's Docket No.: 005794 ALRT/ETCH/CONE/  
Confirmation No.: 3777

Patent

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of: )  
 )  
Mark N. Kawaguchi, et al. )  
 ) Examiner: Olsen, Allan W.  
Application No: 09/978,121 )  
 ) Art Unit: 1763  
Filed: October 15, 2001 )  
 )  
For: A METHOD OF PHOTORESIST )  
REMOVAL IN THE PRESENCE )  
OF A DIELECTRIC LAYER )  
HAVING A LOW K-VALUE )

Mail Stop: RCE  
Commissioner For Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

AMENDMENT AND RESPONSE TO FINAL OFFICE ACTION

Dear Sir:

This is in response to the Final Office Action mailed December 23, 2003, and the Request for Continued Examination (RCE) under 37 C.F.R. § 1.114 filed concurrently herewith. Applicant respectfully requests the Examiner to enter this Amendment and consider the following remarks.

FIRST-CLASS CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first-class mail with sufficient postage in an envelope addressed to Mail Stop: RCE, Commissioner for Patents, P. O. Box 1450, Alexandria, VA 22313-1450, on:

March 23, 2004

Date of Deposit

Dianne Neathery

Name of Person Mailing Correspondence

Dianne Neathery  
Signature

March 23, 2004

Date

Response to Final Office Action  
BSTZ Ref: 004887.P578

- 1/12-

Examiner: Olsen, Allan W.  
Docket: 005794 ALRT/ETCH/CONE/